

Environmental Protection Agency

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PART 469—ELECTRICAL AND ELECTRONIC COMPONENTS POINT SOURCE CATEGORY

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AUTHORITY: Secs. 301, 304, 306, 307, 308, and 501 of the Clean Water Act (the Federal Water Pollution Control Act Amendments of 1972, as amended by the Clean Water Act of 1977, 33 U.S.C. 1311, 1314, 1316, 1317, 1318, and 1361; 86 Stat. 816, Pub. L. 92-500; 91 Stat. 1567, Pub. L. 95-217, unless otherwise noted.

SOURCE: 48 FR 15394, Apr. 8, 1983, unless otherwise noted.

Subpart A—Semiconductor Subcategory

§ 469.10 Applicability.

The provisions of this subpart are applicable to discharges resulting from all process operations associated with the manufacture of semiconductors, except sputtering, vapor deposition, and electroplating.

§ 469.11 Compliance dates.

The compliance deadline for the BAT fluoride limitation shall be as soon as possible as determined by the permit writer, but no later than November 8, 1985. The compliance deadline for the BAT and BCT limitations for total toxic organics (TTO) and pH, respectively, is as soon as possible as determined by the permit writer, but in no event later than July 1, 1984. The compliance date for PSES for TTO is July 1, 1984.

§ 469.12 Specialized definitions.

The definitions in 40 CFR part 401 and the chemical analysis methods in 40 CFR part 136 apply to this subpart.

In addition,

(a) The term "total toxic organics (TTO)" means the sum of the concentrations for each of the following

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toxic organic compounds which is found in the discharge at a concentration greater than ten (10) micrograms per liter:

- 1,2,4 Trichlorobenzene chloroform
- 1,2 Dichlorobenzene
- 1,3, Dichlorobenzene
- 1,4, Dichlorobenzene ethylbenzene
- 1,1,1 Trichloroethane methylene chloride naphthalene
- 2 Nitrophenol phenol bis (2-ethylhexyl) phthalate tetrachloroethylene toluene trichloroethylene
- 2 Chlorophenol
- 2,4 Dichlorophenol
- 4 Nitrophenol pentachlorophenol di-n-butyl phthalate anthracene
- 1,2 Diphenylhydrazine isophorone butyl benzyl pthalate
- 1,1 Dichloroethylene
- 2,4,6 Trichlorophenol carbon tetrachloride
- 1,2 Dichloroethane
- 1,1,2 Trichloroethane dichlorobromomethane

(b) The term "semiconductors" means solid state electrical devices which perform functions such as information processing and display, power handling, and interconversion between light energy and electrical energy.

(c) The term "manufacture of semiconductors" means those processes, beginning with the use of crystal wafers, which lead to or are associated with the manufacture of semiconductor devices.

[48 FR 15394, Apr. 8, 1983, as amended at 48 FR 45250, Oct. 4, 1983]

§ 469.13 Monitoring.

(a) In lieu of monitoring for TTO, the permitting authority may allow direct dischargers to include the following certification as a "comment" on the Discharge Monitoring Report required by §122.44 (i), formerly §122.62(i): "Based on my inquiry of the person or persons directly responsible for managing compliance with the permit limitation for total toxic organics (TTO), I certify that, to the best of my knowledge and belief, no dumping of concentrated toxic organics into the wastewaters has occurred since filing the last discharge monitoring report. I further certify that this facility is implementing the solvent management plan submitted to the permitting authority."

(b) In requesting that no monitoring of TTO be required, the direct dis-

charger shall submit a solvent management plan that specifies to the permitting authority's satisfaction the toxic organic compounds used; the method of disposal used instead of dumping, such as reclamation, contract hauling, or incineration; and procedures for assuring that toxic organics do not routinely spill or leak into the wastewater. The permitting authority shall incorporate the plan as a provision of the permit.

(c) In lieu of monitoring for TTO, the control authority may allow industrial users of POTWs to make the following certification as a comment to the periodic reports required by §403.12(e): "Based on my inquiry of the person or persons directly responsible for managing compliance with the pretreatment standard for total toxic organics (TTO), I certify that, to the best of my knowledge and belief, no dumping of concentrated toxic organics into the wastewaters has occurred since filing the last discharge monitoring report. I further certify that this facility is implementing the solvent management plan submitted to the control authority."

(d) In requesting that no monitoring be required, industrial users of POTWs shall submit a solvent management plan that specifies to the control authority's satisfaction the toxic organic compounds used; the method of disposal used instead of dumping, such as reclamation, contract hauling, or incineration; and procedures for assuring that toxic organics do not routinely spill or leak into the wastewater.

(Approved by the Office of Management and Budget under control number 2040-0074)

[48 FR 15394, Apr. 8, 1983, as amended at 50 FR 4515, Jan. 31, 1985]

§ 469.14 Effluent limitations representing the degree of effluent reduction attainable by the application of the best practicable control technology currently available (BPT).

Except as provided in 40 CFR 125.30 through 125.32 any existing point source subject to this subpart must achieve the following effluent limitations representing the degree of effluent reduction attainable by the application of the best practicable control technology currently available (BPT):